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PATENT  
ATTORNEY DOCKET NO.: 053848-5018

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yoshijiro USHIO et al.

Application No.: 10/774,623

Filed: February 10, 2004

For: METHOD AND DEVICE FOR  
SIMULATION, METHOD AND  
DEVICE FOR POLISHING, METHOD  
AND DEVICE FOR PREPARING  
CONTROL PARAMETER OR  
CONTROL PROGRAM, POLISHING  
SYSTEM, RECORDING MEDIUM,  
AND METHOD OF MANUFACTURING  
SEMICONDUCTOR DEVICE

Confirmation No.: 1365

Group Art Unit: 3723

Examiner: Jacob K. Ackun

Commissioner for Patents  
U.S. Patent and Trademark Office  
Customer Service Window, Mail Stop AF  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314

Sir:

**AMENDMENT UNDER 37 C.F.R. § 1.116**

In response to the Final Office Action dated March 27, 2006, the period for response to which extends through June 27, 2006, and pursuant to 37 C.F.R. § 1.116, entry of the following amendment is respectfully requested to place the application in clear condition for allowance or, alternatively, in better form for appeal.